



Docket No.: 9323.050.00-US  
(PATENT)

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

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In re Patent Application of:

In-Kwon Jeong

Confirmation No.: 1220

Application No.: 09/917,344

Group Art Unit: 1763

Filed: July 27, 2001

Examiner: Sylvia Macarthur

For: CMP SYSTEM AND METHOD FOR  
EFFICIENTLY PROCESSING  
SEMICONDUCTOR WAFERS

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Customer No.: 30827

**RCE AMENDMENT**

Mail Stop RCE  
Commissioner for Patents  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Final Office Action dated November 3, 2006 and the Advisory Action dated February 27, 2007, please amend the above-identified application as follows:

**Amendments to the Claims** are reflected in the listing of the claims which begins on page 2 of this paper.

**Remarks** begin on page 19 of this paper.